

FIG. 2

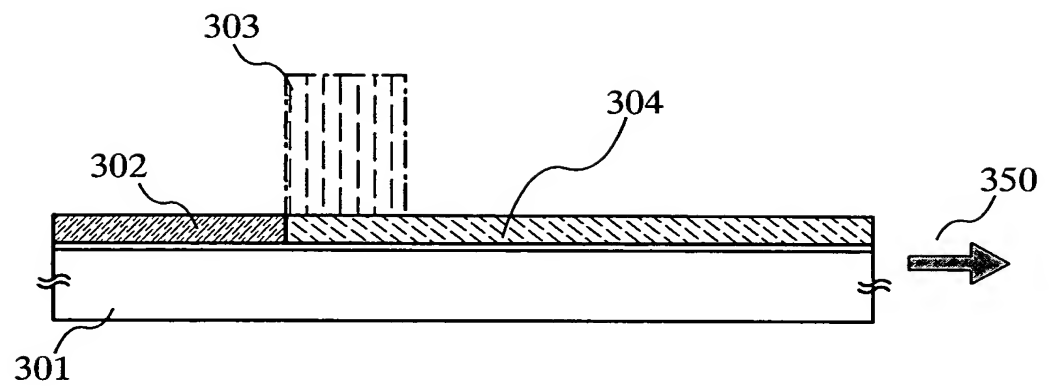


FIG. 3A

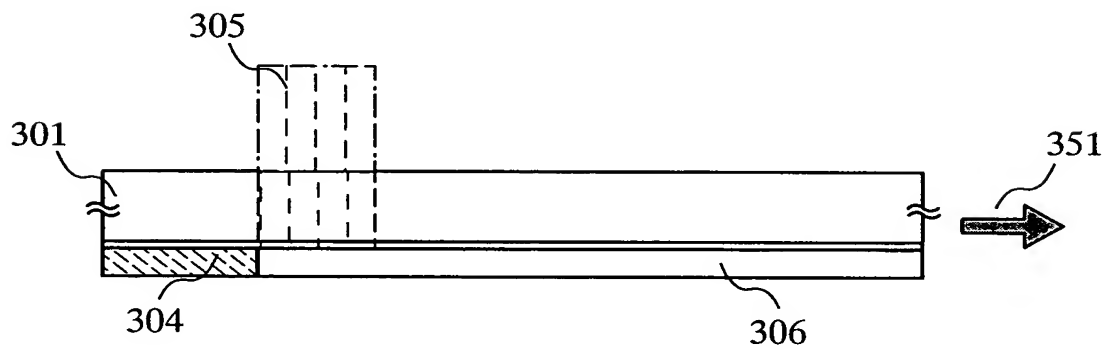


FIG. 3B

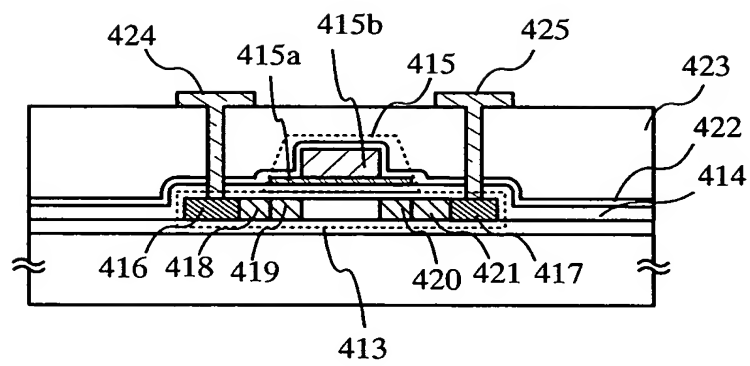


FIG. 4

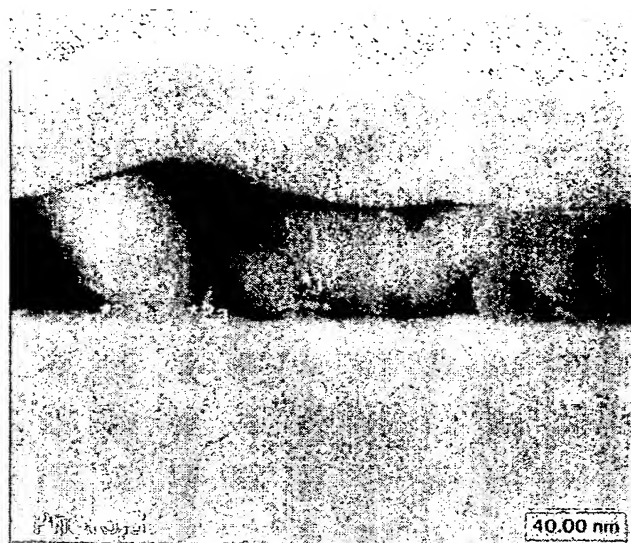


FIG. 5A

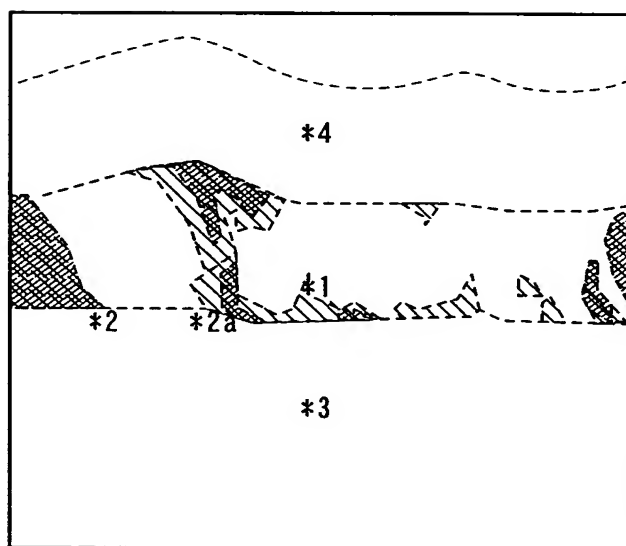
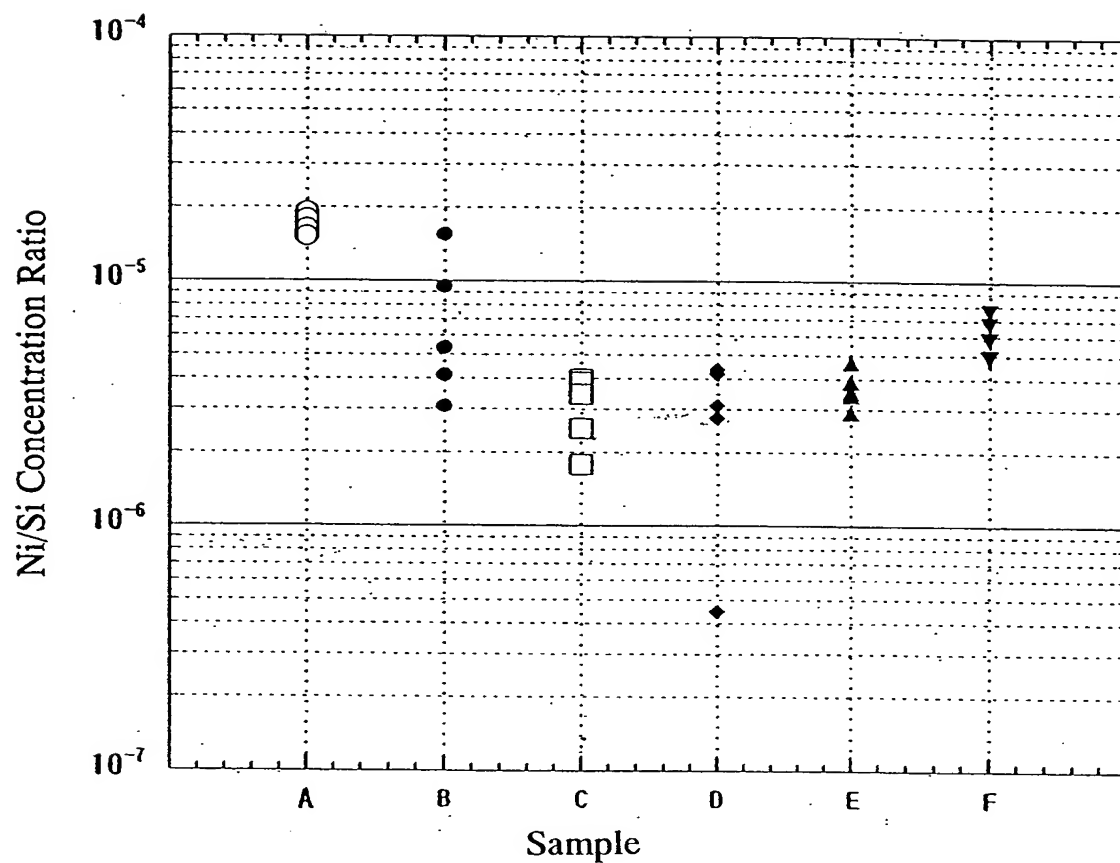
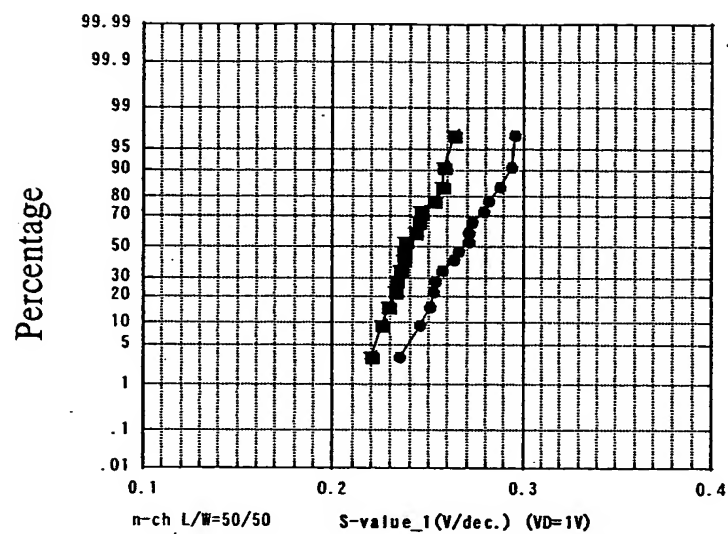


FIG. 5B



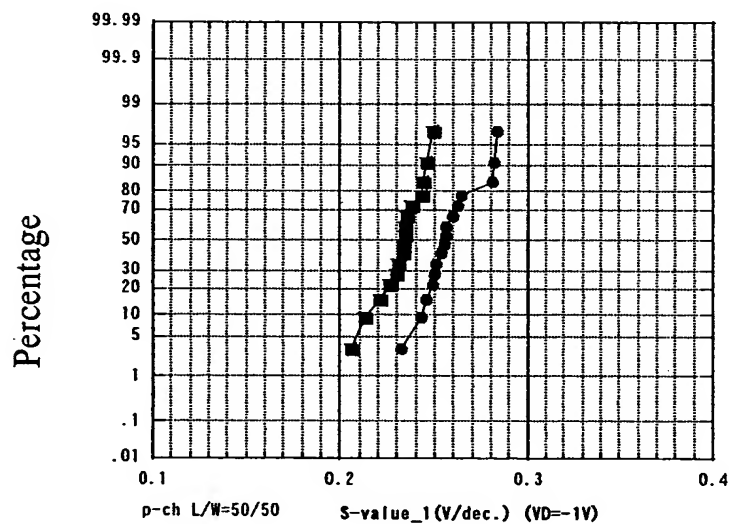
- A; solid phase epitaxy with element
- B; solid phase epitaxy with element + laser annealing (XeCl (485mJcm^{-2}))
- C; solid phase epitaxy with element + laser annealing (XeCl (485mJcm^{-2})+YAG (100mJcm^{-2}))
- ◆ D; solid phase epitaxy with element + laser annealing (XeCl (485mJcm^{-2})+YAG (125mJcm^{-2}))
- ▲ E; solid phase epitaxy with element + laser annealing (XeCl (485mJcm^{-2})+YAG (150mJcm^{-2}))
- ▼ F; solid phase epitaxy with element + laser annealing (XeCl (485mJcm^{-2})+YAG (200mJcm^{-2}))

FIG. 6



- solid phase epitaxy with metal element + laser annealing (XeCl (485mJcm⁻²))
- solid phase epitaxy with metal element + laser annealing (XeCl (485mJcm⁻²)+YAG (150mJcm⁻²))

FIG. 7A



- solid phase epitaxy with metal element + laser annealing (XeCl (485mJcm⁻²))
- solid phase epitaxy with metal element + laser annealing (XeCl (485mJcm⁻²)+YAG (150mJcm⁻²))

FIG. 7B

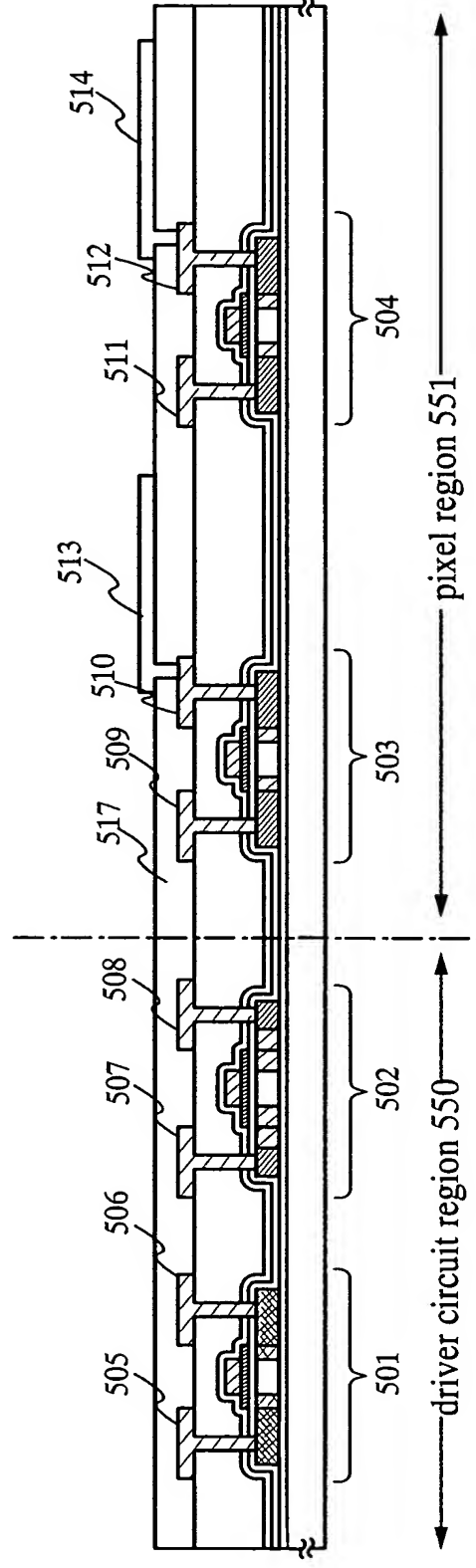


FIG. 8

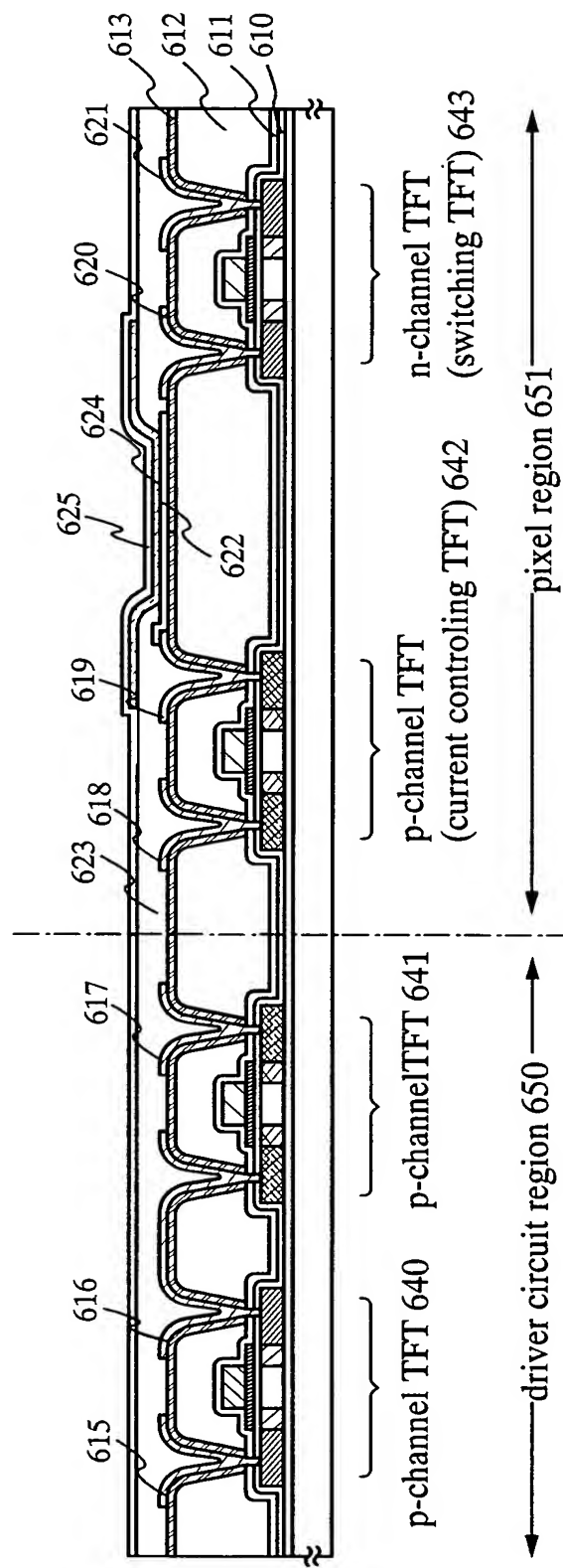
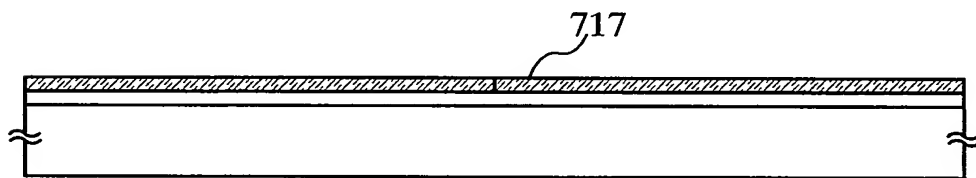
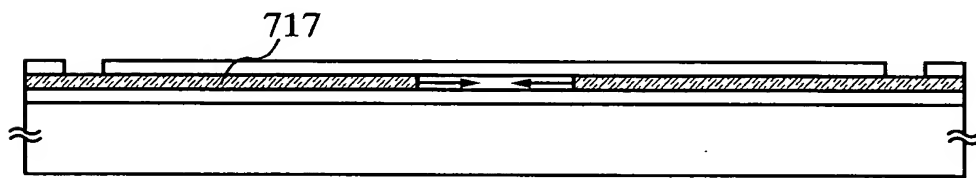
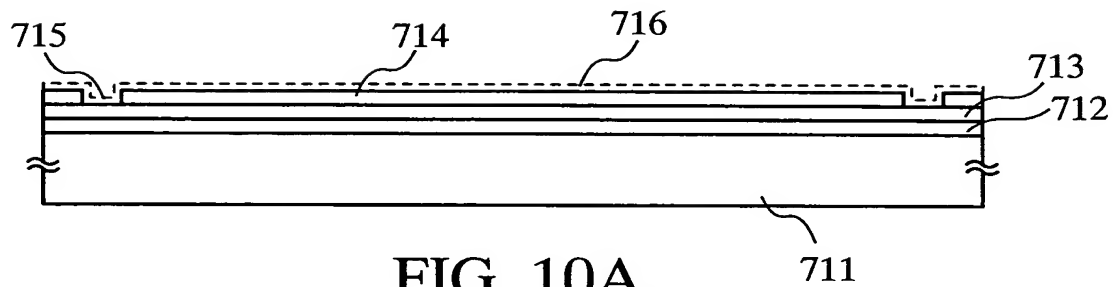


FIG. 9



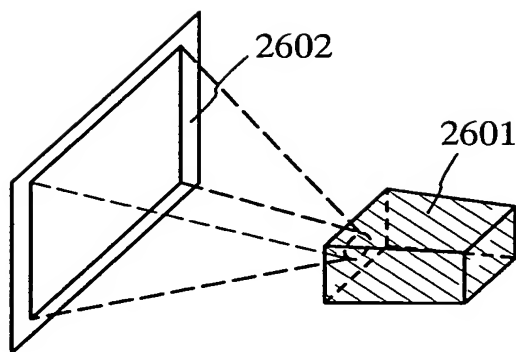


FIG. 11A

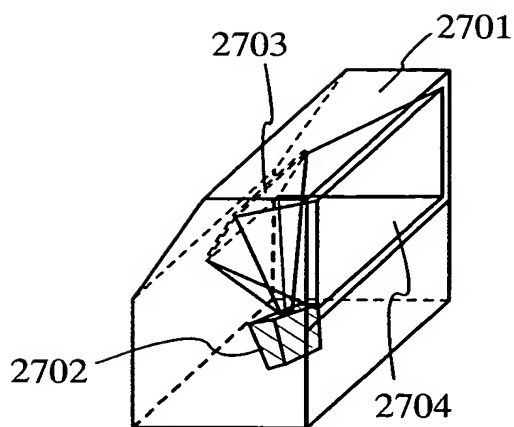


FIG. 11B

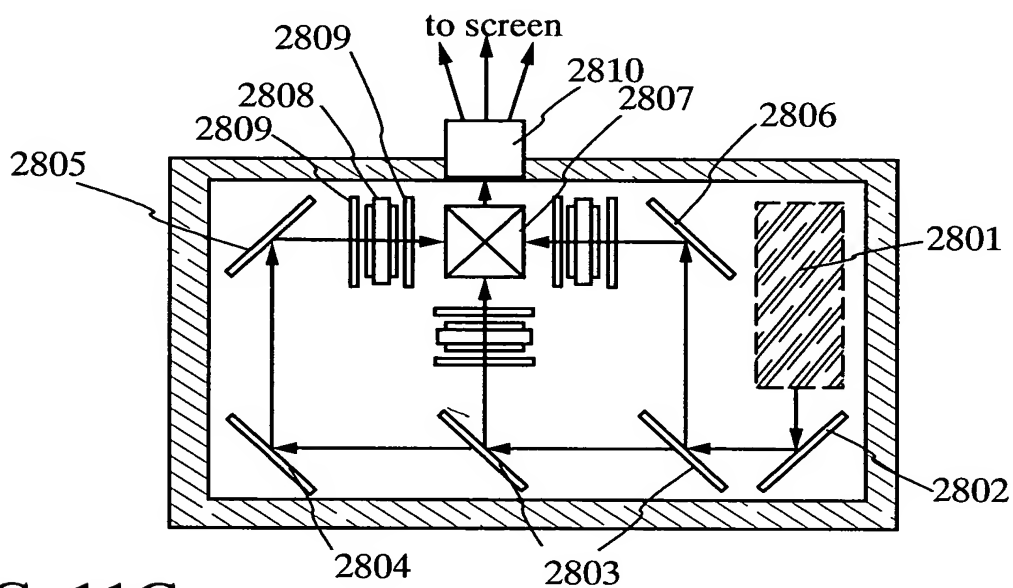


FIG. 11C

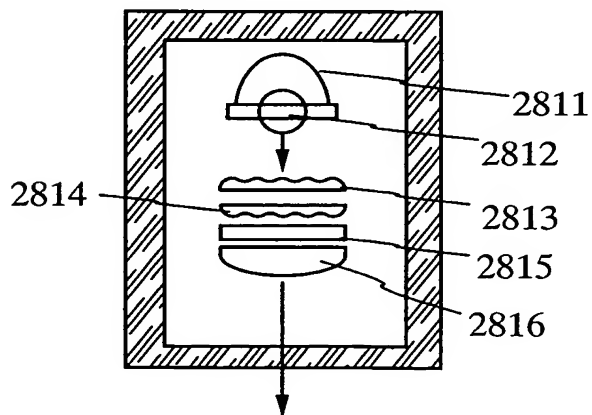


FIG. 11D